



THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/500,214 Confirmation No. : 2535
First Named Inventor : Takuya SUGAWARA
Filed : June 28, 2004
TC/A.U. : 2823
Examiner : Michelle Estrada

Docket No. : 010986.55104US
Customer No. : 23911

Title : Substrate Treating Method and Production Method for
Semiconductor Device

REPLY

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated June 24, 2005, the period for response having been extended to November 24, 2005 by the attached Petition for Extension of Time, please amend the above-captioned application as follows.

Amendments to the Specification begin on page 3 of this paper. A Substitute Specification with marked up version is submitted concurrently herewith.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Amendments to the Drawings are discussed at page 9, and Substitute drawings are included in the Appendix to this paper.

Amendments to the Abstract are discussed beginning at page 10, and include a replacement Abstract in the Appendix to this paper.

Remarks begin on page 11 of this paper.

An **Appendix** including a substitute Abstract, a substitute version of the specification, a marked up version of the specification, and replacement drawing figures is attached following page 15 of this paper.